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Barry Lee-Mean Yang et al.

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-2701-1762

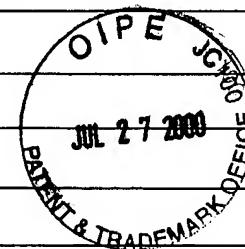
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EXAMINER INITIAL	DOCUMENT NUMBER							DATE	NAME		CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>JEP</i>	AA	3	6	2	5	8	4	8	12/07/71	Snaper	204	192	
	AB	5	5	7	1	3	3	2	11/05/96	Halpern	118	723 HC	
	AC												
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						YES	No
<i>JEP</i>	AL	3 0 1 4 2 5 8	10/15/81	Germany			
	AM	0 8 8 7 4 3 7	12/30/98	EPO			
	AN						
	AO						
	AP						

OTHER INFORMATION (Including Author, Title, Date, Pertinent pages, Etc.)

<i>JEP</i>	AR	Database WPI, Derwent Publications Class A09, AN 1993-411476 XP-002138601, "Light Source Apparatus for Weather Resistant Testing of Organic Material", JP 05312715 A, (1993). <i>abstract</i>					
	AS						
	AT	<i>Barry Lee-Mean Yang et al. 5/23/03</i>					
EXAMINER			DATE CONSIDERED	<i>8/04/03</i>			

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EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA 3 1 6 1 6 1 5	12/15/64	Goldberg			
	AB 3 2 2 0 9 7 3	11/30/65	Goldberg			
	AC 3 3 1 2 6 5 9	04/04/67	Kurkji et al.			
	AD 3 3 1 2 6 6 0	04/04/67	Kurkji et al.			
	AE 3 3 1 3 7 7 7	04/11/67	Elam et al.			
	AF 3 5 7 6 6 5 6	04/27/71	Webb et al.			
PLP	AG 3 6 6 6 6 1 4	06/24/69	Snedeker et al.			
	AH 3 9 8 9 6 7 2	11/02/76	Vestergaard			
	AI 4 1 9 4 0 3 8	03/18/80	Baker et al.			
	AJ 4 2 0 0 6 8 1	04/29/80	Hall et al.			
PLP	AK 4 2 1 0 6 9 9	07/01/80	Schroeter et al.			

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EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES	TRANSLATION NO
	AL 9 2 1 3 5 1 7	02/04/92	PCT				
	AM 8 9 0 1 9 5 7	08/22/88	PCT				
PLP	AN 9 7 1 3 8 0 2	10/11/96	PCT				
	AO						
	AP						

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PLP	AR	S. Anders et al., "Formation of Metal-Oxides by Cathodic-Arc Deposition," 76-77 <u>Surface and Coatings Technology</u> , 167-73 (1995).
PLP	AS	H. Bolt et al., "Gradient Metal - a-C:H Coatings Deposited From Dense Plasma by a Combined PVD/CVD Process," 98 <u>Surface and Coatings Technology</u> , 1518-1523 (1998). pages
PLP	AT	D.E. Brodie et al., "Characterization of ZnO for the Fabrication of Conductor-Insulator-Semiconductor (CIS) Solar Cells," Conf. Proc. for IEEE 14th Photovoltaic Spec. Conf. 468-471 (Jan 7-10, 1980).

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*EXAMINER INITIAL	DOCUMENT NUMBER							DATE	NAME	CLASS	SUBCLASS	GROUP	FILING DATE IF APPROPRIATE
MHD	BA	4	2	2	4	3	7	8	09/23/80	Schroeter et al.			
	BB	4	2	4	2	3	8	1	12/30/80	Goossens et al.			
	BC	4	4	5	4	2	7	5	06/12/84	Rosenquist			
	BD	4	8	4	2	9	4	1	06/27/89	Devins et al.			
	BE	4	8	7	1	5	8	0	10/03/89	Schram et al.			
	BF	4	9	2	7	7	0	4	05/22/90	Reed et al.			
	BG	4	9	4	8	4	8	5	08/14/90	Wallsten et al.			
	BH	5	0	0	8	1	4	8	04/16/91	Thurm et al.			
	BI	5	0	5	1	3	0	8	09/24/91	Reed et al.			
	BJ	5	1	5	6	8	8	2	10/20/92	Rzad et al.			
X	MHD	BK	5	2	9	8	5	8	03/29/94	Hu et al.			

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	BL							
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*EXAMINER INITIAL	DOCUMENT NUMBER							DATE	NAME		CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	CA	5	3	2	0	8	7	5	06/14/94	Hu et al.			
	CB	5	4	3	3	7	8	6	07/18/95	Hu et al.			
	CC	5	4	6	3	0	1	3	10/31/95	Tokuda et al			
	CD	5	4	8	0	7	2	2	01/02/96	Tomonaga et al.			
	CE	5	4	9	4	7	1	2	02/27/96	Hu et al.			
	CF	5	5	1	0	4	4	8	04/23/96	Fontane et al.			
	CG	5	6	1	4	2	4	8	03/25/97	Schiller et al.			
	CH	5	6	3	5	0	8	7	06/03/97	Schiller et al.			
	CI	5	7	1	8	9	6	7	02/17/98	Hu et al.			
	CJ												
	CK												

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	CL							
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OTHER INFORMATION (Including Author, Title, Date, Pertinent pages. Etc.)

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<i>MSP</i>	AU	D.A. Gerdeman and N.L. Hecht, <u>Arc Plasma Technology in Materials Science</u> , 1700 (1972). <i>pages no month</i>
	AV	S. Jager et al., <u>Comparison of Transparent Conductive Oxide Thin Films Prepared by A.C. and D.C. Reactive Magnetron Sputtering</u> , 98 Surface and Coatings Technology, 1304-1314 (1998). <i>pages no month</i>
	AW	Jianhua Hu and Roy G. Gordon, <u>Deposition of Boron Doped Zinc Oxide Films and Their Electrical and Optical Properties</u> , 139 J. Electrochem. Soc., 2014-2022 (1992). <i>Vol. 139, No. 7, pages July</i>
	AX	Z.-C. Jin et al., <u>Optical Properties of Sputter-Deposited ZnO:A1 Thin Films</u> , 61 J. Appl. Phys., 5117-5131 (1988). <i>pages Nov. 15, 64(10),</i>
	AY	R.A. MacGill et al., <u>Cathodic Arc Deposition of Copper Oxide Thin Films</u> , 78 Surface and Coatings Technology, 168-72 (1996). <i>no month</i>
	AZ	S. Major et al., <u>Electrical and Optical Transport in Undoped and Indium-doped Zinc Oxide Films</u> , 1, J. Mater. Res., 300-310 (1986). <i>1(2), pages Mar/Apr</i>
	BU	S. Major et al., <u>Highly Transparent and Conducting Indium-Doped Zinc Oxide Films by Spray Pyrolysis</u> , 108, Thin Solid Films, 333-340 (1983). <i>pages no month</i>
	BV	S. Maniv et al., <u>Transparent Conducting Zinc Oxide and Indium-Tin Oxide Films Prepared by Modified Reactive Planar Magnetron Sputtering</u> , A1 J. Vac. Sci. Tech., 1370-1375 (1983). <i>1(3), pages July/Sept</i>
	BW	Tadatsugu Minami et al., <u>Group III Impurity Doped Zinc Oxide Thin Films Prepared by RF Magnetron Sputtering</u> , 24, Japanese J. of Appl. Phys., L781-L784, (1985). <i>Vol. 24, No. 10, pages Oct</i>
	BX	Tadatsugu Minami et al., <u>Highly Conductive and Transparent Silicon Doped Zinc Oxide Thin Films Prepared by RF Magnetron Sputtering</u> , 25 Japanese J. of Appl. Phys., L776-L779, (1986). <i>Sept Vol. 25, No. 9, pages</i>
	BY	M. Miyazaki and E. Ando, <u>Durability Improvement of Ag-Based Low-Emissivity Coatings</u> , 178, J. Non-Crystalline Solids, 245-249 (1994). <i>pages no month</i>
<i>MSP</i>	BZ	C.X. Qiu and I. Shih, <u>Tin- and Indium-Doped Zinc Oxide Films Prepared by RF Magnetron Sputtering</u> , 13 Solar Energy Materials, 75-84 (1986). <i>pages no month</i>

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RD-25,993

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<i>M.L.Y.</i>	CU	D. Raviendra and J.K. Sharma, "Electroless Deposition of Cadmium Stannate, Zinc Oxide, and Aluminum-Doped Zinc Oxide Films," <u>58 J. Appl. Phys.</u> , 838-844 (1985). <u>58(2)</u> , <u>pages</u> <u>July</u>
✓	CV	R.E.I. Schropp et al., "Transparent and Conductive Thin Films of ZnO for Photovoltaic Applications Prepared by RF Magnetron Sputtering," <u>Conf. Rec. of 20th IEEE Photovoltaic Spec. Conf.</u> 273-276 (Sept. 26, 1988).
✓	CW	B.E. Sernelius et al., Band-Gap Tailoring of ZnO by Means of Heavy Al Doping, <u>37 Physical Review B of Am. Phys. Soc.</u> , 10244-10248 (1998). <u>pages</u> <u>June 15, 1988</u> <u>Vol 37, No. 17,</u>
✓	CX	I. Shih and C.X. Qiu, "Indium-Doped Zinc Oxide Thin Films Prepared by RF Magnetron Sputtering," <u>58 J. Appl. Phys.</u> , 2400-2401 (1985). <u>58(6)</u> , <u>pages</u> <u>Sept. 15</u>
✓	CY	S. Sreedhara Reddy et al., "Optical Properties of Spray Deposited ZnO Films," <u>71 Solid State Communications</u> , 899-901 (1991). <u>pages</u> <u>normonth</u> <u>Vol. 77, No. 12,</u>
✓	CZ	K.J. Saunders, <u>Organic Polymer Chemistry</u> , 388-411 (2d ed. 1988) <u>pages</u> <u>except for</u> <u>normonth</u>
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